



U.S. PATENT & TRADEMARK OFFICE
WASHINGTON, D.C. 20531

Our ~~Serial~~ No: 42390P10058

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Han-Ming Wu et al.

Examiner: Nguyen, Hung

Serial No: 09/752,938

Art Unit: 2851

Filed: December 29, 2000

For: Purging Gas from a Photolithography
Enclosure Between a Mask Protective
Device and a Pattern Mask

RESPONSE TO OFFICE ACTION

Box Non Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Office Action mailed April 29, 2002 the Applicants respectfully request the Examiner to enter the following amendments and to consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Assistant Commissioner for Patents, Washington, D. C. 20231

July 29, 2002

Date of Deposit

Debbie Peloquin

Name of Person Mailing Correspondence

Debbie Peloquin
Signature

July 29, 2002

Date

Docket No.: 42390P10058
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